The sessions, presentations and presenters making up this year's MEMS Forum were as follows.

Session 1 : Strengthening the MEMS Industrial Base

(1) The Opening of the MEMS Industry

- Tsuneyuki Miyake (Associate editor for Microdevices, Nikkei Business Publications Inc.)
- (2) Case Study: Training of Personnel to Promote Applied MEMS in the MOT Project Research

Kiyoshi Itao (Professor, Tokyo University of Science) (3) MEMS Personnel Training and Technologies for Commercial Application of MEMS

- Ryutaro Maeda (Senior Researcher, Advanced Manufacturing Process Department, National Institute of Advanced Industrial Science and Technology [AIST])
- (4) Features of MemsONE (MEMS Design / Analysis Support System) and Case Studies
- Hidetoshi Kotera (Professor, Kyoto University) (5) Overview of Activities to Create a MEMS Foundry Network Kazushi Tomii, Chair, Foundry Service Industry Committee, MEMS Industry Forum

(Matsushita Electric Works Ltd.)

Session 2 : Industry-Academia Collaboration

(1) Use of MEMS and Biochips Produced through Micro/Nano Stereolighography

Shoji Maruo (Professor, Graduate School of Engineering, Yokohama National University) (2) Workshop on 3D Integration Using Hetero Wafer Bonding Tadatomo Suga (Professor, Graduate School, The University of Tokyo)

(3) Organizations for Interdisciplinary / New Domain Research Activities: Inauguration of Dedicated Micro/Nano Engineering Forum

Hidetoshi Kotera (Professor, Kyoto University)

Session 3 : Asia MEMS Forum

(1) MEMS in China Mainland

Dong F.Wang (Senshu University, Ishinomaki, Japan) (2) Micro/Nano Technology in Korea

Young-Ho Cho (KIST, Korea) (3) MEMS & Nanotechnology in Taiwan

M. S. Lin (Industrial Technology Research Institute [ITRI]) (4) MEMS Industry Forum (MIF) Towards Virtuous Cycle of the MEMS Industry Growth of Asia

Junji Adachi (Micromachine Center, Japan)

Session 4 : Research Results

(1) MEMS Market Research Report

Shunichi Adegawa (General Manager, Industry Department, Micromachine Center)

(2) Report of Outcome Survey, Micromachine Project Shinichi Tamura (Manager, Survey Research No. 2 Section, Research Department,

Japan Technical Information Services Corporation) (3) BEANS (Toward the Achievement of 3rd Generation MEMS)

Junji Adachi (General Manager, Research Department, Micromachine Center)

Fine MEMS Project Interim Achievements Seminar

As one of the events comprising MicroNano 2007, the Fine MEMS Project Interim Achievements Seminar was held on Friday, July 27 at a special venue set up within the West No. 3 Hall at the Tokyo International Exhibition Center (Tokyo Big Sight). As its name implies, the seminar was held to announce the interim achievements of the Highly Integrated / Complex MEMS Manufacturing Technology Development Project (Fine MEMS Project) commissioned and subsidized by the New Energy and Industrial Technology Development Organization (NEDO). The seminar was sponsored by the Fine MEMS Project Committee and the Micromachine Center, and cosponsored by NEDO, with assistance provided by the Ministry of Economy, Trade and Industry (METI).

The seminar opened with greetings from two invited guests: Hiroaki Okahashi, Deputy Director of METI, and Masami Takayasu, Director of NEDO. These greetings were followed by a presentation entitled "Overview of Fine MEMS Project" by Isao Shimoyama, Professor and Dean of the Graduate School of Information Science and Technology at the University of Tokyo. Professor Shimoyama provided an overview of the project's achievements including grant activities. This was followed by



detailed reports of the latest consignment project achievements in eight areas by the project supervisors, which triggered a lively discussion. Following the conclusion of the seminar, a technical consultation corner was set up at the NEDO Highly Integrated / Complex MEMS booth at Exhibition Micromachine/MEMS, affording visitors the opportunity to talk directly with research and development supervisors with the aim of facilitating the practical application of project achievements.

At the seminar, the 130 seats that had been set up at the special venue filled up just as the seminar was about to begin, so an additional 50 seats were hastily provided. However, these also filled up immediately. Judging from the air of excitement that permeated the venue from beginning to end, the expectations for this project are extremely high. An opinion survey was conducted for the 126 persons who attended the seminar and 219 persons who visited the exhibition booth. The results will be analyzed and will serve to spur efforts aimed at rapidly achieving practical applications for the manufacturing technologies developed in the course of the project.

